

Form PTO-1449

INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(Use several sheets if necessary)

Docket Number (Optional)
3640.2US (97-1175.02/US)Application Number
N t y t assignedApplicant **St v n J. Simm ns**Filing Date **August 29, 2003**Group Art Unit **Unkn wn**

U.S. PATENT DOCUMENTS

| EXAMINER INITIAL | DOCUMENT NUMBER | DATE | NAME | CLASS | SUBCLASS | FILING DATE IF APPROPRIATE |
|---------------------|-----------------|---------|------------------|-------|----------|-------------------------------|
| <i>BSL</i> | 4,376,583 | 03/1983 | Alford et al. | | | |
| <i>BSL</i> | 5,103,166 | 04/1992 | Jeon et al. | | | |
| <i>BSL</i> | 5,127,726 | 07/1992 | Moran | | | |
| <i>BSL</i> | 5,240,866 | 08/1993 | Friedman et al. | | | |
| <i>BSL</i> | 5,294,812 | 03/1994 | Hashimoto et al. | | | |
| <i>BSL</i> | 5,301,143 | 04/1994 | Ohri et al. | | | |
| <i>BSL</i> | 5,539,752 | 07/1996 | Berezin et al. | | | |
| <i>BSL</i> | 5,544,256 | 08/1996 | Brecher et al. | | | |
| <i>BSL</i> | 5,777,901 | 07/1998 | Berezin et al. | | | |
| <i>BSL</i> | 6,265,232 | 07/2001 | Simmons | | | |
| <i>BSL</i> | 6,479,305 | 11/2002 | Kono et al. | | | |
| <i>BSL</i> | 6,485,991 | 11/2002 | Jitramas et al. | | | |
| <i>BSL</i> | 6,492,189 | 12/2002 | Yamaguchi | | | |
| <i>BSL</i> | 6,613,590 | 09/2003 | Simmons | | | |

FOREIGN PATENT DOCUMENTS

| | DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUBCLASS | Translation | |
|--|-----------------|------|---------|-------|----------|-------------|----|
| | | | | | | YES | NO |
| | | | | | | | |
| | | | | | | | |
| | | | | | | | |

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

| | | |
|------------|--|--|
| <i>BSL</i> | | S.L. Riley, "Optical Inspection of Wafers Using Large-Area Defect Detection and Sampling", The IEEE International Workshop on Defect and Fault Tolerance in VLSI Systems, November 4-6 1992, pps. 12-21. |
| <i>BSL</i> | | KLA 255X Software V3.6 Option Release Notes, "Automatic Clustering and Sampling of Defects", 19 pages. <i>NO DATE.</i> |
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EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance. Include copy of this form with next communication to the applicant.